Search Notes				

Application No.	Applicant(s)
10/611,862	IWASAKI ET AL.
Examiner	Art Unit
Stephen W. Smoot	2813

	0545	OUED		
SEARCHED				
Class	Subclass	Date	Examiner	
257	412	3/4/2004	sws	
257	413	3/4/2004	sws	
257	762	3/4/2004	sws	
257	766	3/4/2004	sws	
257	768	3/4/2004	sws	
257	769	3/4/2004	sws	
257	774	3/4/2004	sws	
438	620	3/4/2004	sws	

INTERFERENCE SEARCHED				
Class	Subclass	Date	Examiner	
	I			

SEARCH NOTES (INCLUDING SEARCH STRATEGY)			
	DATE	EXMR	
Considered All Citations and Search Reports from Parent Applications.	3/4/2004	S.W.S. sws	
Key Words: Copper Interconnect - Multilayer Film - Layer of Platinum, Iridium, Osmium, Rhodium, Ruthenium;	3/4/2004	J.V.L. sws	
Plus Additive of Cobalt, Nickel, Palladium, Titanium;	3/4/2004	S.V.S. sws	
Contact to Source/drain or Gate; Gate Electrode Including Layer of Platinum, Iridium, Osmium, Rhodium, Ruthenium	3/4/2004	1. V. 3.	
Search Tools - EAST (attached): USPAT; US PG PUBS; Derwent; EPO; JPO; IBM TDB	3/4/2004	S.W.S sws	